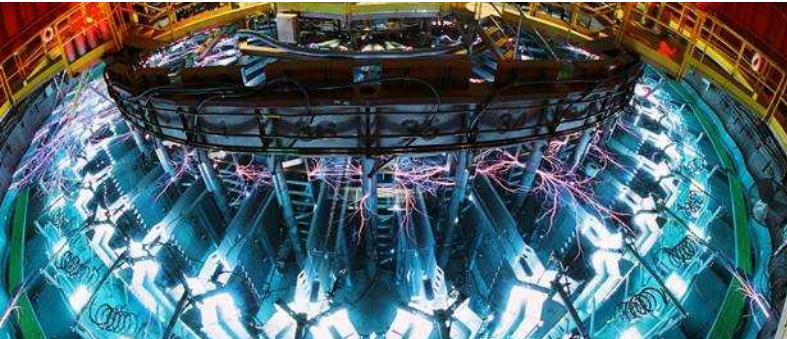


*Exceptional service in the national interest*



# Silicon Anode Gas Generation Questions



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# ICL During Formation in Model System

Electrolyte: EC:DEC 3:7 (wt%) 30 wt% FEC, 1.2 M LiPF<sub>6</sub>

Scan rate: 0.2 mV/s

cut off voltage: 2 V – 0.005 V

Cycle #: 11

Sample area: ~0.33 cm<sup>2</sup>

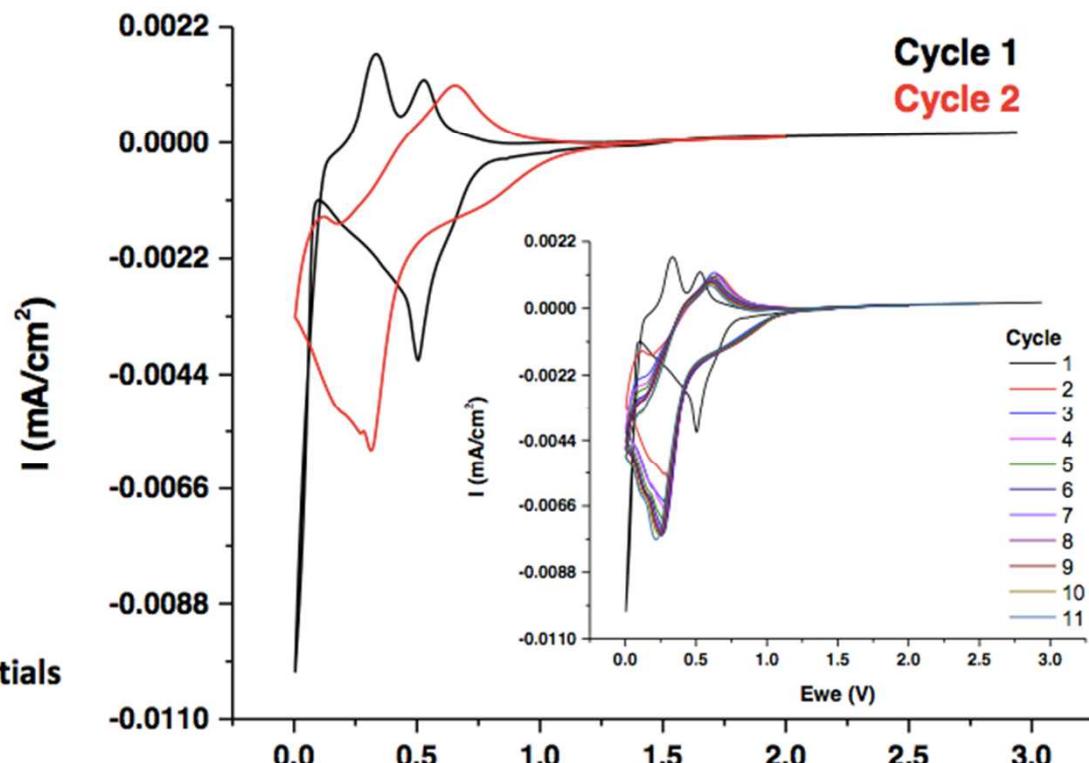
Charge consumption  
[mC/cm<sup>2</sup>]

Cycle 1	
total	-90.53
cathodic	-112.34
anodic	21.81
2-0.29 V	-64.07
0.29-0.2 V	-45.51
0.2-2V	18.96

**No surface passivation.**

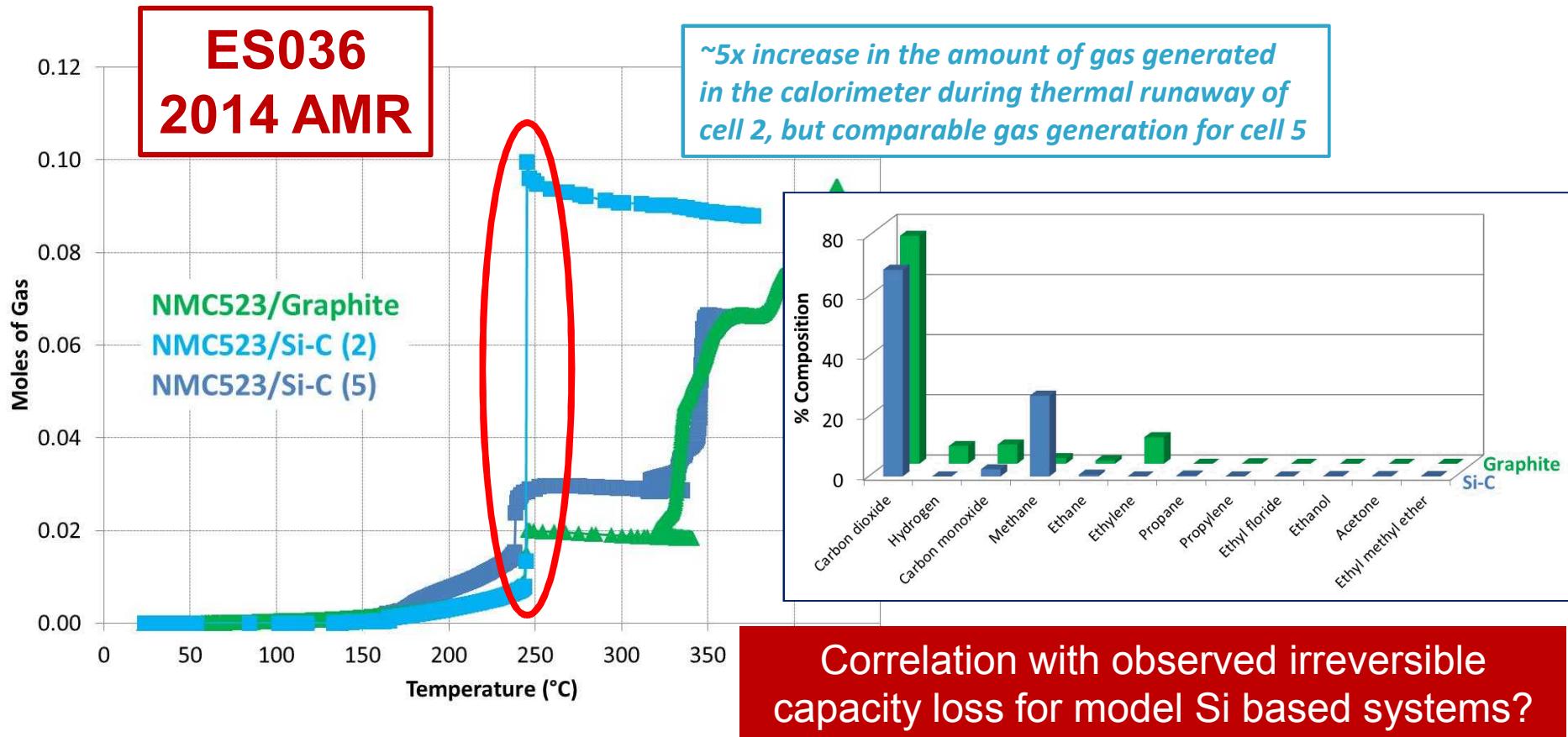
**Reduction shifted to lower potentials**

Possible scenarios:



Significant losses observed during formation cycling in model systems (copper and silicon). Electrochemical reduction of binder/electrolyte? Can this be correlated to gas generation seen in full electrode ensembles?

# Abuse Response of Silicon Anodes



***Difference in gas generation attributed to the differences in surface reactivity and surface products generated at the anode/electrolyte interface***

# Approach

1. Spin-coat binder and carbon phases on both Cu and p-Si wafer substrates.
2. Carry out electrochemical measurements of model thin-film electrodes in baseline electrolyte(s).
3. Ex situ evaluations for gas generation using DSC/TGA and grab samples during electrochemical and abuse evaluations.
4. Perform similar treatment for electrode ensembles to determine correlation between model system and industry relevant electrodes.

